

OEC



Opto-Electronic
Components



Soft X-Ray, Deep UV Enhanced Series

Inversion Layer Silicon Photodiodes

Features

- Direct Detection
- No Bias Needed
- High Quantum Efficiency
- Low Noise
- High Vacuum Compatible
- Cryogenically Compatible
- 0.070nm to 1100nm Wavelength Range

Applications

- Electron Detection
- Medical Instrumentation
- Dosimetry
- Radiation Monitoring
- X-ray Spectroscopy
- Charged Particle Detection

OSI Optoelectronics' 1990 R&D 100 award winning X-UV detector series are a unique class of silicon photodiodes designed for additional sensitivity in the X-Ray region of the electromagnetic spectrum without use of any scintillator crystals or screens. Over a wide range of sensitivity from 200 nm to 0.07 nm (6 eV to 17,600 eV), one electron-hole pair is created per 3.63eV of incident energy which corresponds to extremely high stable quantum efficiencies predicted by $E_{ph}/3.63eV$ (See graph below). For measurement of radiation energies above 17.6 keV, refer to the "Fully Depleted High Speed and High Energy Radiation Detectors" section.



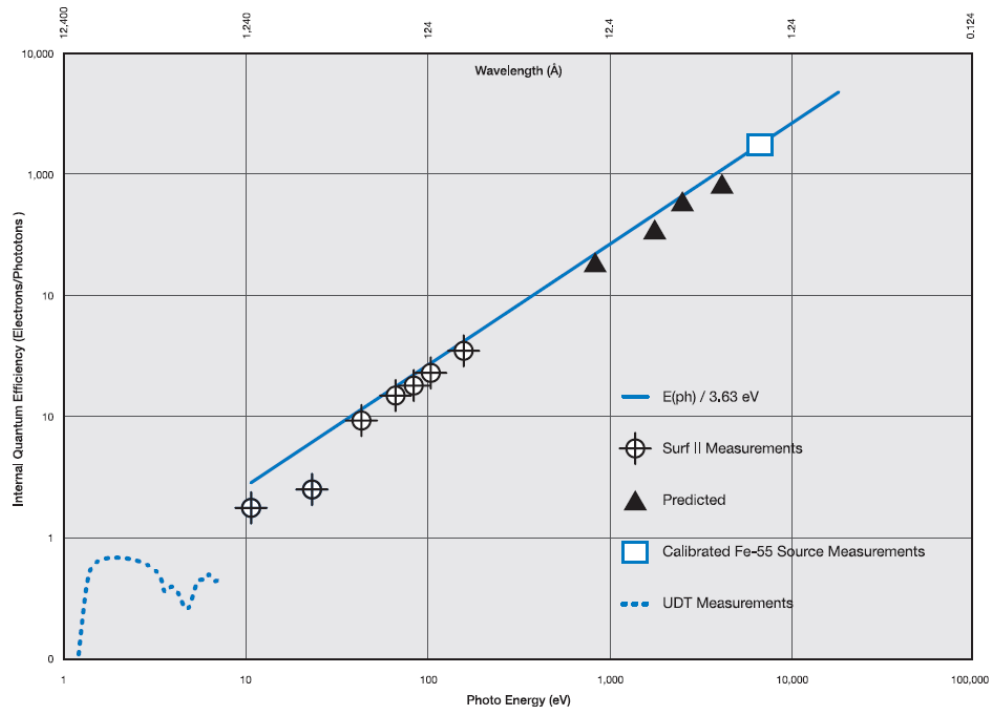
A reverse bias can be applied to reduce the capacitance and increase speed of response. In the unbiased mode, these detectors can be used for applications requiring low noise and low drift. These detectors are also excellent choices for detecting light wavelengths between 350 to 1100 nm.

The detectors can be coupled to a charge sensitive preamplifier or low-noise op-amp as shown in the circuit on the opposite page.

YOUR PARTNER



Typical Quantum Efficiency



Typical Electro-Optical Specifications at $T_A=23^\circ\text{C}$

Model Number	Active Area		Capacitance (nF) 0V		Shunt Resistance ($M\Omega$) -10mV	
	Area (mm ²)	Dimensions (mm)	Typ	Max	Min	Typ
'XUV' Series Metal Package						
XUV-005	5	2.57 ϕ	0.3	0.5	200	2000
XUV-020	20	5.00 ϕ	1.2	1.6	50	500
XUV-035	35	6.78 x 5.59	2	3	30	300
XUV-100	100	11.33 ϕ	6	8	10	100
'XUV' Series Ceramic Package						
XUV-50C	50	8.02 ϕ	2	3	20	200
XUV-100C	100	10.00 sq	6	8	10	100

OEC



Opto-Electronic
Components



Model Number	NEP (W/√Hz)		Temp. Range (°C) *		Package Style
	0V, 200nm		Operating	Storage	
	Typ	Max			
'XUV' Series Metal Package					
XUV-005	2.9 e-15	9.1 e-15	-20 ~ +60	-20 ~ +80	22/ TO-5
XUV-020	5.8 e-15	1.8 e-14			23/ TO-8
XUV-035	7.4 e-15	2.3 e-14			28/ BNC
XUV-100	1.3 e-14	4.1 e-14			
'XUV' Series Ceramic Package					
XUV-50C	9.1 e-15	2.9 e-14	-20 ~ +60	-20 ~ +80	25/ Ceramic
XUV-100C	1.3 e-14	4.1 e-14			

All XUV devices are supplied with removable windows.

* Non-Condensing temperature and Storage Range, Non-Condensing Environment
For mechanical drawings please refer to "Mechanical Drawings".

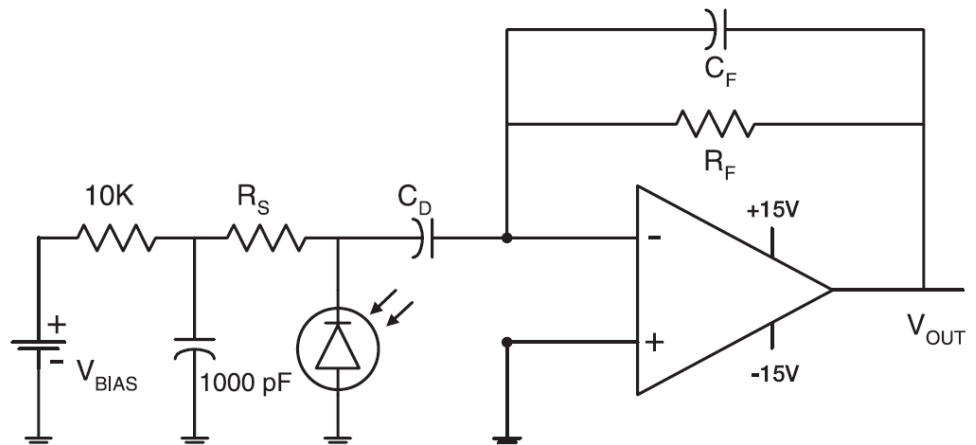
In this circuit example, the pre-amplifier is a FET input op-amp or a commercial charge sensitive preamplifier. They can be followed by one or more amplification stages, if necessary. The counting efficiency is directly proportional to the incident radiation power. The reverse bias voltage must be selected so that the best signal-to-noise ratio is achieved.

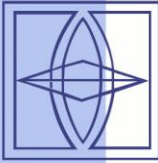
For low noise applications, all components should be enclosed in a metal box. Also, the bias supply should be either simple batteries or a very low ripple DC supply.

Amplifier: OPA-637, OPA-27 or similar
 R_F : 10 M Ω to 10 G Ω
 R_S : 1 M Ω ; Smaller for High Counting Rates
 C_F : 1pF
 C_D : 1pF to 10 μ F

OUTPUT $V_{OUT} = Q / C_F$

Where Q is the Charge Created by One Photon or One Particle





Reverse Bias:

The XUV devices can be operated with a small reverse bias in applications where fast response time is critical. We do not recommend using a reverse bias higher than 5V. Therefore to improve the response time you can use a reverse bias of up to 5V on the detector.

Impact of Reverse Bias on NEP and Bandwidth:

Applying a reverse Bias will reduce the junction Capacitance of the device resulting in Higher Bandwidth. Also The reverse Bias will increase the dark current of the detector which in turn will increase the NEP.

The exact relation and the calculation of the NEP and Capacitance are explained in the attached application notes.